



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Docket No: Q68577

Akihiro HASHIGUCHI

Appln. No.: 10/076,447

Group Art Unit: 1752

Confirmation No.: 9868

Examiner: Thorl CHEA

Filed: February 19, 2002

For: THERMAL DEVELOPMENT SYSTEM AND APPARATUS

AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner for Patents  
Washington, D.C. 20231

Sir:

In response to the Office Action dated February 13, 2003, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Please replace page 14, 1<sup>st</sup> full paragraph as follows:

As shown in Fig. 4, the inside of the heat processing apparatus 1 is partitioned with the preheating portion I and the developing portion II formed like chambers. An air sucking portion communicating with the outside which is not shown is opened in a chamber portion 26. Moreover, an exhaust path 27 communicating with the outside is coupled to the chamber portion 26. The exhaust path 27 has a deodorizing filter 28 and an exhaust fan 29 provided sequentially from the inside of a chamber portion 26. A gas generated from the preheating portion I and the developing portion II is sucked from the chamber portion 26 into the exhaust path 27, and passes

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